



PATENT

Our Docket: M-CI 4561

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of
Ger van den Engh

Serial No: 09/847,466

Filed: May 1, 2001

For: APPARATUS FOR DETERMINING
RADIATION BEAM ALIGNMENT

Group Art Unit: 287

Examiner: S. Lee

I hereby certify that this correspondence
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Oct. 22, 2002
(date of deposit)

Delbert J. Baer
Signature

Commissioner for Patents
Washington, D.C. 20231

RESPONSE TO OFFICE ACTION

Responsive to the Office Action mailed July 22, 2002, entry
of the following Amendments and Remarks is respectfully
requested.

AMENDMENTS

In the specification

Please replace the paragraph starting on page 20, line 28
and ending on page 21, line 21, with the following paragraph:

B
An apparatus of the invention can be used to determine
alignment of a radiation beam emitted from a flow chamber. A
flow chamber can contain a sample stream in which emission from
molecules or particles is observed when they pass a point of
observation. The point of observation can be placed, for
example, as shown in Figures 2 and 4 as location 4. As shown in
the Figures, radiation emitted at the point of observation, for
example, from fluorescent particles that have been contacted with
radiation of an excitatory wavelength, can be collimated into a
beam. The beam can be directed toward a screen having a mirrored
surface interrupted by one or more pin holes such that alignment

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